

Electronic Acknowledgement Receipt

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Title of Invention:	Chemical vapor deposition apparatus
First Named Inventor/Applicant Name:	Ho Lee
Customer Number:	32605
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Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Amendment After Final	AB-1350US_AMEND.pdf	147846	no	5

Warnings:

Information:	Total Files Size (in bytes):	147846
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<p><u>National Stage of an International Application under 35 U.S.C. 371</u></p> <p>If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.</p>		